

## Dr. Jill S. Becker



Entrepreneur / High Tech Consultant

Nanotechnology

<http://www.directoryinventor.com/profile/view/3v2Qdfkn>

## Experience

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### Consulting Scientist/Founder Cambridge NanoTech

Ultratech/Cambridge NanoTech

201-500 employees; Public Company; Semiconductors

January 2013 - Present

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### Member

YPO-WPO

Nanotechnology

2011 - 2011

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### Trustee

Cambridge Montessori School

Machinery

2010 - 2011

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### Recipient

BBJ 40 Under 40

Nanotechnology

2010 - 2010

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### Board Member

SBANE (Small Business Association of New England)

Nonprofit Organization Management

2009 - 2010

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### Founder, CEO

Cambridge NanoTech Inc.

11-50 employees; Privately Held; Nanotechnology

October 2003 - December 2012

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## Education

## Harvard University

Chemistry

1998 - 2003

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## University of Toronto

Chemistry

1993 - 1997

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## Patents (17)

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### Vapor deposition of silicon dioxide nanolaminates

Roy Gerald Gordon, Jill S Becker, Dennis Hausmann

September 17, 2013: 08536070

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### Vapor deposition of metal oxides, silicates and phosphates, and silicon dioxide

Roy G Gordon, Jill S Becker, Dennis Hausmann, Seigi Suh

December 18, 2012: 08334016

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### Vapor deposition systems and methods (6 worldwide citation)

Douwe J Monsma, Jill S Becker

June 19, 2012: 08202575

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### Vapor deposition of metal oxides, silicates and phosphates, and silicon dioxide

Roy G Gordon, Jill Becker, Dennis Hausmann, Seigi Suh

February 2, 2012: 20120028478-A1

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### Vapor deposition of silicon dioxide nanolaminates

Roy G GORDON, Jill Becker, Dennis Hausmann

November 17, 2011: 20110281417-A1

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### Vapor deposition of silicon dioxide nanolaminates

Roy G Gordon, Jill Becker, Dennis Hausmann

August 30, 2011: 08008743

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### Reaction chamber with removable liner

Roger R Coutu, Jill S Becker, Douwe J Monsma

September 30, 2010: 20100247763-A1

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### Plasma atomic layer deposition system and method

Jill S Becker, Roger R Coutu, Douwe J Monsma

July 22, 2010: 20100183825-A1

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### System and method for thin film deposition

Jill S Becker, Roger R Coutu, Douwe J Monsma

July 1, 2010: 20100166955-A1

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## Vapor deposition of tungsten nitride (3 worldwide citation)

Roy G Gordon, Seigi Suh, Jill Becker

July 14, 2009: 07560581

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[View all \(17\)](#)